

Customer No.: 31561  
Application No.: 10/604,793  
Docket No.: 10573-US-PA

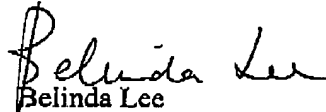
**REMARKS**

In response to the Office Action, mailed on May 18, 2006, a complete listing of all of the claims is presented herewith. Applicant would like to elect Group I, claims 1-18, drawn to a wafer surface ion sampling system, classified in class 134, subclass 94.1. Please cancel Group II, claims 19-22, drawn to a wafer surface ion sampling method, classified in class 134, subclass 34, without waiver, prejudice or disclaimer.

If the Examiner believes that a telephone conference would expedite the examination of the above-identified patent application, the Examiner is invited to call the undersigned.

Date : *June 1, 2006*

Respectfully submitted,

  
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